

<b>Notice of References Cited</b>	Application/Control No. 10/689,042	Applicant(s)/Patent Under Reexamination PATEL	
	Examiner Anita K. Alanko	Art Unit 1765	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
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**FOREIGN PATENT DOCUMENTS**

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	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Zeidler, D. et al "The interaction between different barrier metals and the copper surface during the chemical-mechanical polishing" Microelectronic Engineering, 1997, 37/38, 237-243.
	V	
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	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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